

**The Sixth International Conference on Hot-Wire Chemical  
Vapor Deposition (Cat-CVD) Process will be held  
September 13-17, 2010 in Ecole Polytechnique, Palaiseau, France**  
<http://hwcvd6.polytechnique.fr/>

### TOPICS

This conference is designed to promote synergies between Hot-Wire Chemical Vapor Deposition researchers working on different materials (semiconductors, metal oxides, organics, etc...) and addressing different applications (solar cells, sensors, industrial coatings, etc...).

HWCVD (also known as Catalytic CVD, Hot Filament CVD, and more recently Initiated CVD) allows to achieve high quality silicon related materials (amorphous, nanocrystalline, polycrystalline and epitaxial), silicon alloys (nitrides, oxides, carbides), passivation coatings, thin film diamond, hard coatings, nanostructured carbon, carbon nanotubes, transition metal oxide nano-particles, and polymers. Device applications of HWCVD films include thin film transistors, solar cells, light emitting diodes, gas sensors, electrochromic windows, organic devices, and micromechanical structures. Contributions using Hot-Wire chambers for dry etching, surface passivation, or chamber cleaning are also welcome.

Common themes will be process fundamentals (nucleation, coalescence, surface roughening, etc...), technical improvements (filament lifetime, etc...), new developments (process, apparatus), and technology transfer (industrial implementation).

### CONFERENCE LOCATION

Ecole Polytechnique, amphitheater Pierre Faurre, Palaiseau (near Paris)

### KEY DATES

Deadline for abstract submission	April 1, 2010
Notification of acceptance	May 15, 2010
Advanced registration for attendees and exhibitors	July 1, 2010
Deadline for manuscript submission	July 15, 2010

## ABSTRACTS

Submit your **200 word abstract** to :

[http://hwcdv6.polytechnique.fr/abstract\\_submission.php](http://hwcdv6.polytechnique.fr/abstract_submission.php)

In the form of an attached pdf file. Please follow the attached template which is available on the web site. Indicate whether you prefer an oral or poster presentation.

## PROCEEDINGS

The proceedings of the previous conferences appeared as special issues of *Thin Solid Films*: Vol. 395 (September 2001), Vol. 430 (April 2003), Vol. 501 (April 2006), Vol. 516 (January 2008) and Vol. 517 (April 2009). All attendees of the sixth conference will receive the corresponding hardbound volume.

## HWCVD6 secretariat

[hwcdv6@gmail.com](mailto:hwcdv6@gmail.com) LPICM-CNRS, Ecole Polytechnique, 91128 Palaiseau, France

## INVITED SPEAKERS (to be confirmed)

### Committee Members

#### Conference Chairman

Jean-Eric Bourée (CNRS-Ecole Polytechnique, France)

#### Local Arrangement Committee

Enric Garcia-Caurel (CNRS-Ecole Polytechnique, France)

Chantal Geneste (CNRS-Ecole Polytechnique, France)

Frédéric Liège (CNRS-Ecole Polytechnique, France)

Eric Paillassa (CNRS-Ecole Polytechnique, France)

Carine Roger-Roulling (CNRS-Ecole Polytechnique, France)

Denis Tondelier (CNRS-Ecole Polytechnique, France)

#### International Organizing Committee

Jean-Eric Bourée (CNRS-Ecole Polytechnique, France)

Karen K. Gleason (Massachusetts Institute of Technology, USA)

A. Harv Mahan (National Renewable Energy Laboratory, USA)

Hideki Matsumura (Japan Advanced Institute of Science and Technology, Japan)

Hiroshi Nakayama (Osaka City University and Material Design Factory Co., Japan)

Shuichi Nonomura (Gifu University, Japan)

Bernd Schroeder (University of Kaiserslautern, Germany)

Ruud E.I. Schropp (Utrecht University, The Netherlands)

### **International Advisory Committee**

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Rajiv Dusane (Indian Inst. Tech. Bombay, India)  
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Dorel Toma (Tokyo Electron America, USA)  
Hironobu Umemoto (Shizuoka Univ., Japan)  
Mitch Ushijima (Tokyo Electron Ltd., Japan)  
Jeff Yang (United Solar Ovonic Corp., USA)